

EV633261929

Inventor: **Gary J. Derderian et al.**

Title: **Atomic Layer Deposition Methods, and Methods of Forming Materials Over Semiconductor Substrates**

Assignee: **Micron Technology, Inc.**

Serial No.: **10/671,922**

Filed: **September 24, 2003 [RCE Filed Herewith]**

**INFORMATION DISCLOSURE STATEMENT**

**PURSUANT TO 37 C.F.R. §§ 1.56, 1.97 AND 1.98**

The attached Form PTO-1449 is submitted in compliance with 37 CFR §1.56. Pursuant to FEDERAL REGISTER, Vol. 69, No. 182, pg. 56542 (September 21, 2004), no copies of any cited U.S. patents or U.S. published applications are included herewith. No admission is made regarding whether the listed reference is prior art.

Citation of this patent is respectfully requested.

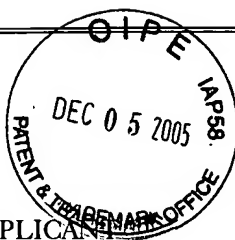
Respectfully submitted,

Dated: 12/5/03

By: 

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Form PTO-1449

U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICELIST OF ART CITED BY APPLICANT  
(Use several sheets if necessary)ATTY. DOCKET NO.  
MI22-2296SERIAL NO.  
10/671,922APPLICANT  
Garo J. Derderian et al.FILING DATE  
Sept. 24, 2003 [RCE filed herewith]GROUP  
2812

## U.S. PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	6,812,157 B1	11/04	Gadgil			
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						

## FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Sub-class	Translation	
							Yes	No
	AK							
	AL							

## OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

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